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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
TOSHICHIKA TAKEI, ET AL. : EXAMINER: LUU, C.
SERIAL NO: 10/774,419 :
FILED: FEBRUARY 10, 2004 : GROUP ART UNIT: 2892
FOR: HEAT PROCESSING APPARATUS :
AND HEAT PROCESSING METHOD

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

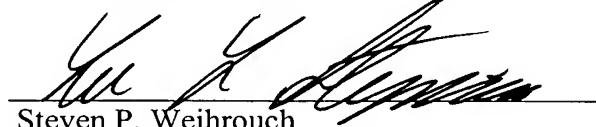
The Examiner's Statement of Reasons for Allowance included at page 2 of the Notice of Allowability mailed June 3, 2008, characterizes the claimed inventions in terms of "a frame member disposed on the first side of the heating plate so as to overlap the heating plate as viewed from the first side, the frame member including an inner peripheral surface directly opposite the side of the mask substrate such that a first clearance is disposed between the inner peripheral surface and the side surface, the frame member being detachably supported by the heating plate so that the frame member is disposed around the mask substrate, and the frame member and mask substrate are disposed within the same plane that is parallel to the front surface of the heating plane..."

However, Applicant respectfully notes that the above-noted language appears to be specifically directed to independent Claim 1. Applicant further respectfully notes that, for example, independent Claim 7 does not recite that the frame member is disposed on the first side of the heating plate so as to overlap the heating plate as viewed from the first side..."

Accordingly, Applicants understand the Examiner's Statement of Reasons for Allowance to apply to independent Claim 1 and the claims depending therefrom, but not to independent Claim 7 and the claims depending therefrom.

Respectfully submitted,

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